APÊNDICE E

PUBLICAÇÕES EM METROLOGIA: PESQUISA POR TÍTULOS

A seguir são apresentados os resultados das pesquisas por obras em temas de metrologia, realizadas nos sites de duas livrarias virtuais, que se destacam no comércio eletrônico de livros e publicações: www.amazon.com e www.bn.com, em 16/05/2002.

Quadro E.1: pesquisa por publicações no site www.amazon.com

NOME	AUTOR	MÊS/ANO
1990 Proceedings: Particle Detection Metrology and Control International Conference		June 1990
1997 2nd International Workshop on Statistical Metrology	Japan International Workshop on Statistical Metrology 1997 Kyoto	January 1998
1997 2nd International Workshop on Statistical Metrology, June 8, 1997, Kyoto		
2nd European Congress on Optics Applied to Metrology (METROP): presented as part of the Optics, Photonics, and Iconics Engineering Meeting (OPIEM), November 26-30, 1979, Strasbourg, France		
3rd Symposium of the Technical Committee (TC8) on Theoretical Metrology, Berlin, GDR, 15-17 Oct. 1986: proceedings		
A history of engineering metrology	K. J. Hume	
A Metrological Study of the Early Roman Basilicas (Mellen Studies in Architecture, 8)	Christopher Vaughan Walthew	March 2002
Accurate Visual Metrology from Single and Multiple Uncalibrated Images (Distinguished Dissertations (Springer-Verlag))	Antonio Criminisi	September 2001
Advanced Mathematical & Computational Tools in Metrology IV (Series on Advances in Mathematics for Applied Sciences, 52)	P. Ciarlini (Ed.), et al	June 2000
Advanced Mathematical and Computational Tools in Metrology V (Series on Advances in Mathematics for Applied Sciences, Vol. 57)	P. Ciarlini (Ed.), et al	May 2001
Advanced Mathematical Tools in Metrology II (Series on Advances in Mathematics for Applied Sciences, Vol 40)	P. Ciarlini (Ed.), et al	July 1996
Advanced Mathematical Tools in Metrology III (Series on Advances in Mathematics for Applied Sciences, Vol 45)	P. Ciarlini (Ed.), et al	June 1997
Advanced Mathematical Tools in Metrology: Proceedings of the International Workshop	P. Ciarlini	May 1994
Advances in Fabrication and Metrology for Optics and Large Optics (Spie Volume 966)	B. Arnold (Ed.), R. E. Parks (Ed.)	January 1989
Advances in Optical Metrology: August 28-29, 1978, San Diego, California		
Advancing Metrology for Electrotechnology to Support the U.S. Economy	Joanne Surrette	June 1997
Amplitude and Intensity Spatial Interferometry	J. Breckinridge (Ed.)	July 1990
Amplitude and Intensity Spatial Interferometry II: 15-16 March 1994 Kona, Hawaii (Spie Proceedings, Vol 2200)	James B. Breckinridge (Ed.)	March 1994
Ancient Metrology	Donald L. Lenzen	November 1989
Applications of Optical Metrology Techniques and Measurements II	John J., Jr. Lee (Ed.)	December 1983
Applications of Speckle Phenomena	William H. Carter (Ed.)	October 1980
Applied Radio nuclide Metrology	W. B. Mann (Ed.), et al	December 1983
Archaeological Metrology (History and Archaeology, 68)	Lester A. Ross	December 1983
Aspects of Materials Metrology and Standards for Structural Performance	B. F. Dyson, et al	September 1993
Basic Metrology for ISO 9000 Registration	G. M. S. de Silva	
Characterization and Metrology for Ulsi Technology: 1998 International Conference (AIP Conference Proceedings, Vol. 449)	David G. Seiler (Ed.), et al	December 1998
Characterization and metrology for Ulsi technology: 1998 international conference, Gaithersburg, Maryland, March 1998		
Characterization and Metrology for Ulsi Technology: 2000 International Conference (AIP Conference Proceedings)	D. G. Seiler (Ed.), et al	February 2001
Christopher Columbus, Cosmographer: A History of Metrology, Geodesy, Geography, and Exploration from Antiquity to the Columbian Era	Fred F. Kravath	April 1988
Coherent Optical Metrology	Richard Kowarschik, et al	
Comprehensive Mass Metrology	Manfred Kochsiek (Ed.), Michael Glaser (Ed.)	January 2000
Critical Issues in Scanning Electron Microscope Sem Metrology	Michael T. Postek	June 1994
Dimensional Metrology and Geometric Conformance: A Selection from the Tool and Manufacturing Engineers Handbook	Charles Wick, Raymond F. Veilleux	June 1989

	(Ed.)	
Discovering the system of mosaical metrology	Eliyahu Metzler	
Electromagnetic Metrology: Proceedings of International Symposium on Electromagnetic Metrology, ISEM '89, August 19-22, 1989 Beijing, China	International Symposium on Electromagnetic Metrology	February 1990
Engineering metrology	K. J. Hume	
Engineering metrology	Geoffrey Gladstone Thomas	
Engineering Metrology (Pergamon Materials Engineering Practice Series)	D. M. Anthony	June 1987
European metrology	Nigel Pennick	
First European Conference on Optics Applied to Metrology, October 26-28, 1977, Strasbourg (France)		
Fixed Gages Dividers, Calipers and Micrometers. Module 27-2 (Metrology Ser.)		June 1979
Flat Panel Display Technology and Display Metrology: 27-29 January 1999, San Jose, California (Proceedings of Spie--The International Society for opt	Bruce Edward Gnade (Ed.), Edward F. Kelley (Ed.)	April 1999
Frequency Standards and Metrology: Proceedings of the Fourth Symposium Ancona Italy September 6-9 1988	A. De Marchi (Ed.)	June 1989
Frequency Standards and Metrology: Proceedings of the Sixth Symposium Held in St. Andrews, Fife, Scotland on September 9-14, 2001	Patrick Gill (Ed.)	June 2002
Fundamental of Dimensional Metrology	Busch	August 1974
Fundamentals of Dimensional Metrology	Roger H., Jr., Harlow, et al	
Gear Metrology	C. A. Scoles	
Giovanni Giorgi and his contribution to electrical metrology: proceedings of the meeting held in Turin (Italy) on 21 and 22, September 1988		
Gravitational Measurements, Fundamental Metrology, and Constants (NATO Asi Series, Series C: Mathematical and Physical Sciences, Vol 230)	Venzo De Sabbata, V.N. Melnikov (Ed.)	June 1988
Handbook of Critical Dimension Metrology and Process Control: Proceedings of a Conference Held 28-29 September 1993 Monterey, California (Critical R)	Kevin M. Monahan, et al (Ed.)	December 1994
Handbook of Silicon Semiconductor Metrology	A. C. Diebold (Ed.)	June 2001
Handbook of Surface Metrology	David J. Whitehouse	December 1997
Historical Metrology	Algernon Edward. Berriman	June 1953
Hologram Interferometry and Speckle Metrology Proceedings November 5-8, 1990 Baltimore Maryland		November 1990
Holographic and Speckle Interferometry		August 1987
Holographic and Speckle Interferometry (Cambridge Studies in Modern Optics, No 6)	Robert Jones	January 1989
Holographic Interferometry: Principles and Methods (Akademie Verlag Series in Optical Metrology, Vol 1)	Thomas Kreis	April 1996
Imaging and Illumination for Metrology and Inspection: 2-4 November 1994, Boston, Massachusetts (Proceedings of Spie--The International Society for o	Donald J. Svetkoff (Ed.), Society of Photo-Optical Instrumentation	June 1995
In Process Optical Metrology for Precision MacHining (Spie Proceedings, Volume 802)	Peter Langenbeck	March 1987
Industrial Applications for Optical Data Processing and Holography	Edgar Conley (Ed.), Jean Robillard (Ed.)	August 1992
Industrial Applications of Holographic and Speckle Measuring Techniques: 12-13 March, 1991, the Hague, the Netherlands Ec04 (Spie Proceedings Series)	Werner P. Jueptner (Ed.)	December 1991
Industrial Applications of Optical Inspection, Metrology and Sensing (Proceedings of S P I E, Vol 1821)	H.P. Stahl, et al	November 1992
Industrial Metrology: Surfaces and Roundness	Graham T. Smith	May 2002
Industrial Optical Sensing and Metrology: Applications and Integration: 10 September 1993 Boston, Ma. / Volume 2066	Kevin G. Harding	October 1994

Industrial Optical Sensors for Metrology and Inspection: 31 October-1 November 1994, Boston, Massachusetts (Proceedings of Spie--The International so	Kevin G. Harding (Ed.), et al	June 1995
Industrial Vision Metrology: 11-12 July, 1991, Winnipeg, Manitoba (Canada)	Sabry F. El-Hakim (Ed.)	December 1991
Integrated Circuit Metrology	D. Nyyssonen (Ed.)	August 1982
Integrated Circuit Metrology and Process Control		July 1994
Integrated Circuit Metrology II (Proceedings of Spie-International Society for Optical Engineering, Vol 480)	Diana Nyyssonen (Ed.)	July 1984
Integrated Circuit Metrology Inspection and Process Control Viii/V 2196	Mary Bennett (Ed.)	May 1994
Integrated Circuit Metrology, Inspection and Process Control II (Spie, Vol 921)	K. M. Monahan	August 1988
Integrated Circuit Metrology, Inspection and Process Control IX: 20-22 February 1995, Santa Clara, California	Marylyn H. Bennett (Ed.), Society of Photo-Optical Instrumentation en	February 1995
Integrated Circuit Metrology, Inspection, and Process Control (Proceedings of Spie--The International Society for Optical Engineering, Vol 775)	Kevin M. Monahan (Ed.)	July 1987
Integrated Circuit Metrology, Inspection, and Process Control III: 27-28 February 1989, Los Angeles, California (Spie Proceedings, Vol 1087)	Kevin M. Monahan (Ed.)	July 1989
Integrated Circuit Metrology, Inspection, and Process Control IV (Spie Proceedings, Vol 1261)	William H. Arnold (Ed.)	December 1990
Integrated Circuit Metrology, Inspection, and Process Control VI: 9-11 March 1992 San Jose, California (Spie Proceedings, Vol 1673)	Michael T. Postek (Ed.)	May 1992
Integrated Circuit Metrology, Inspection, and Process Control, V: Proceedings (Proceedings of Spie, Vol 1464)	William H. Arnold	July 1991
Interferometric Metrology (Spie, Vol 816)	N. A. Massie (Ed.)	June 1988
Interferometry in Speckle Light: Theory and Applications: Proceedings of the International Conference 25-28 September 2000, Lausanne, Switzerland	P. Jacquot (Ed.), J.M. Fournier (Ed.)	October 2000
International Conference On Applied Optical Metrology: 8-11 June 1998, Balatonfured, Hungary (Proceedings Of Spie--The International Society for Optical Metrology)	International Conference on Applied Optical Metrology	August 1998
International Conference on Photomechanics and Speckle Metrology (Spie, Vol 814)	Fu-Pen Chiang (Ed.)	February 1988
International Conference on Speckle: August 20-23, 1985, San Diego, California (Spie, Vol 556)	International Conference on Speckle	August 1985
International vocabulary of basic and general terms in metrology = Vocabulaire international des termes fondamentaux et généraux de métrologie		
Internationales Wèorterbuch der Metrologie = International vocabulary of basic and general terms in metrology		
IWSM: 1998 3rd International Workshop on Statistical Metrology : June 7, 1998, Honolulu		
IWSM 1999 International Workshop on Statistical Metrology: June 12, 1999/Kyoto		November 1999
Landmarks in metrology-1983: proceedings of a program sponsored by ISA's Metrology Division entitled "re-presentation of papers, originally presented within the last thirty years, which have demonstrated a lasting technical importance": ISA '83 international conference & exhibit, Houston, Texas.		October 10-13, 1983
Laser Dimensional Metrology: Recent Advances for Industrial Application: Proceedings 5-7 October 1993 Brighton United Kingdom/Volume 2088	M. Downs	
Laser Metrology & Machine Performance V	G. N. Peggs (Ed.), National Physical Laboratory	July 2001
Laser Metrology and Inspection (Europto)	Hans J. Tiziani (Ed.), Pramod K. Rastogi (Ed.)	September 1999
Laser Metrology and Machine Performance	D.M.S. Blackshaw, et al	June 1993

Laser Metrology and Machine Performance II: Laser Metrology and Machine Performance II	A.D. Hope	July 1995
Laser Metrology and Machine Performance III	D. G. Ford (Ed.), S. R. Postlethwaite (Ed.)	December 1997
Laser Metrology and Machine Performance IV	Vic Chiles (Ed.), D. Jenkinson (Ed.)	July 1999
Laser Technology 4: Research Trends, Instrumentation and Applications in Metrology and Materials Processing (Spie Poland Chapter Proceedings, 14)	Wiesaw Wolinski (Ed.), et al	June 1995
Legal Metrology in the Federal Republic of Germany	Wilfried Schulz	
Machine Vision Systems for Inspection and Metrology VII: 4-5 November, 1998, Boston, Massachusetts (Proceedings of Spie--The International Society)	Bruce G. Batchelor (Ed.), et al	October 1998
Machine Vision Systems for Inspection and Metrology VIII: 21-22 September 1999, Boston, Massachusetts (Proceedings of Spie--The International Society)	John W.V. Miller (Ed.), et al	August 1999
Manufacturing Metrology/G00490	G. Sathyanarayanan	January 1989
Material Culture of the Chumash Interaction Sphere: Manufacturing Processes, Metrology and Trade (Ballena Press Anthropological Papers, No 31)	Travis Hudson	November 1987
Materials Metrology and Standards for Structural Performance	M.G. Gee (Ed.), et al	January 1995
Metrology		June 1984
Metrology and Fund Constants 1976	A. Ferro Milone (Author)	
Metrology and fundamental constants [i.e. constants]: Varenna on Lake Como, Villa Monastero, 12th-24th July 1976		
Metrology and Gauging	Stanley Alfred James Parsons	
Metrology and Monitoring of Radon, Thoron and Their Daughter Products (Nea Experts Report)		October 1985
Metrology and Properties of Engineering Surfaces, 1985: Proceedings	K.J. Stout, T.R. Thomas (ed.)	June 1986
Metrology at the Frontiers of Physics and Technology	L. Crovini, T. J. Quinn (Ed.)	
Metrology Course: 27		June 1979
Metrology for Quality Control in Production	Zhaoqian Meng	October 1989
Metrology for Radio-Frequency Technology: A Bibliography	Ruth Marie Lyons (Ed.)	October 1999
Metrology for the Semiconductor Industry (Pb 91240739)	Robert Scace	September 1991
Metrology in industrial instrumentation: proceedings from the 1977 spring industry oriented conference, Anaheim, California		
Metrology of Optoelectronic Systems (Spie Proceedings Volume 776)	Edward M. Granger	May 1987
Metrology Properties Engineered Surfaces	E. Mainsah (Ed.), et al	December 2000
Metrology, Inspection & Process Control for Microlithography XI: 10-12 March 1997 Santa Clara, California (Proceedings of Spie, Vol. 3050)	Susan K. Jones (Ed.)	July 1997
Metrology, inspection, and process control for microlithography X: 11-13 March, 1996, Santa Clara, California		
Metrology, Inspection, and Process Control for Microlithography XII	Bhanwar Singh (Ed.)	June 1998
Metrology, Inspection, and Process Control for Microlithography Xiii: 15-18 March, 1999, Santa Clara, California (Proceedings of Spie)	Bhanwar Singh (Ed.), Society of Photo-Optical Instrumentation Enginee	June 1999
Metrology, Inspection, and Process Control for Microlithography XIV: 28-February-2 March 2000 Santa Clara, California (Proceedings of Spie Volume 399)	Neal T. Sullivan (Ed.)	July 2000
Metrology: Figure and Finish (Proceedings of Spie, the International Society for Optical Engineering, Vol 749)	Bruce Truax (Ed.)	June 1987
Metrology: Proceedings of the 11th Triennial World Congress of the International Measurementation Confederation (IMEKO Houston, Texas, USA 16-21 Oc)		December 1988

Microlithography and Metrology in Micromachining 23 24 October 1995: 23-24 October, 1995, Austin, Texas	Michael T. Postek (Ed.), Semiconductor Equipment and material	September 1995
Microlithography and Metrology in Micromachining II: 14-15 October, 1996, Austin, Texas		
Microlithography and Metrology in Micromachining III: 29-30 September, 1997, Austin, Texas		
Micron and Submicron Integrated Circuit Metrology (Spie Vol 565)	Kevin M. Monahan (Ed.)	December 1985
Microsystems Metrology and Inspection	Christophe Gorecki (Ed.)	September 1999
Microwave Circuit Theory: And Foundations of Microwave Metrology (Electrical Measurement)	Glenn F. Engen	December 1992
Modern Techniques in Metrology		August 1984
Modern Techniques in Metrology	Paul Hewitt (Ed.)	August 1984
Musculoskeletal Clinical Metrology	Nicholas Bellamy	July 1993
Nuclear Data Guide for Reactor Neutron Metrology	J.H. Baard, et al	March 1990
Optical Methods in Engineering Metrology	D.C. Williams (Ed.)	November 1992
Optical Methods in Engineering Metrology		April 1994
Optical Metrology	Kjell J. Gasvik	June 2002
Optical Metrology: Coherent and Incoherent Optics for Metrology, Sensing and Control in Science, Industry, and Biomedicine (NATO Asi Series, Series)	Oliverio D.D. Soares (Ed.)	July 1987
Optical Metrology: Proceedings of a Conference Held 18-19 July, 1999, Denver, Colorado (Critical Reviews of Optical Science and Technology, V. Cr72)	Ghanim A. Al-Jumaily (Ed.), Society of Photo-Optical Instrumentation	July 1999
Optical Microlithography and Metrology for Microcircuit Fabrication: 27-28 April, 1989, Paris, France (Spie Proceedings Series, Vol 1138)	Michel J. Lacombat, Steve Wittekoek (Ed.)	September 1989
Optical Testing and Metrology (Spie Volume 661)	C.P. Grover (Ed.)	November 1986
Optical Testing and Metrology II (Spie, Volume 954)	C. P. Grover	November 1988
Optical Testing and Metrology III: Recent Advances in Industrial Optical Inspection (Spie, Proceedings Series, Vol. 1332)	C.P. Grover (Ed.)	December 1990
Optics in Engineering Measurement (Spie Volume 599)	William F. Fagan (Ed.)	July 1986
Optics in metrology and quality assurance: February 6-7, 1980, Los Angeles, California		
Precision Surface Metrology (Proceedings of Spie-The International Society for Optical Engineering Vol 429)	James C. Wyant (Ed.)	June 1983
Proceedings of the 1993 International Forum on Dimensional Tolerancing and Metrology: presented at the 1993 International Forum on Dimensional Tolerancing and Metrology, Dearborn, Michigan		June 17-19, 1993
Process Module Metrology, Control, and Clustering: 11-13 September, 1991 (Spie Proceedings, Vol. 1594)	Cecil J. Davis, et al	January 1992
Quantum Metrology and Fundamental Physical Constants	NATO Advanced Study Institute on Quantum Metrology and Fundamental	September 1983
Reactor Dosimetry: Radiation Metrology and Assessment (ASTM Special Technical Publication. Stp, 1398)	John G. Williams (Ed.)	February 2001
Recent Advances in Metrology, Characterization, and Standards for Optical Digital Data Disks: 21-22 July 1999, Denver, Colorado (Proceedings of Spie)	Fernando L. Podio (Ed.), Society of Photo-Optical Instrumentation Eng	October 1999
Recent Developments in Optical Gauge Block Metrology: 20-21 July 1998 San Diego, California (Spie Proceedings Series, Volume 3477)	Jennifer E. Decker (Ed.), Nicholas Brown (Ed.)	September 1998
Rhetoric in American Colleges 1850-1900 (Smu Studies in Composition and Rhetoric)	Albert Raymond Kitzhaber	October 1990
Second International Conference on Photomechanics and Speckle Metrology: Speckle Techniques, Birefringence Methods, and Applications to Solid mechani	Fu-Pen Chiang (Ed.), Society of Photo-Optical Instrumentation enginee	December 1991

Selected Papers on Interference, Interferometry, and Interferometric Metrology (Spie Milestone, Vol MS 110)	P. Hariharan, Daniel Malacara (Ed.)	May 1995
Selected Papers on Optical Methods in Surface Metrology (Spie Milestone Series, Vol MS 129)	David J. Whitehouse (Ed.), Brian J. Thompson (Ed.)	August 1996
Selected Papers on Optical Shop Metrology		August 1990
Selected Papers on Optical Shop Metrology (Spie Milestone Series, Vol 18)	Brian J. Thompson (Ed.)	August 1990
Selected Papers on Particle Image Velocimetry (Spie Milestone Series, V MS 99)	Ian Grant (Ed.), Society of Photo-Optical instrumentation	June 1994
Selected Papers on Speckle Metrology (Spie Milestone Series, Vol 35)	Rajpal S. Sirohi (Ed.)	June 1991
Semiconductor Fabrication: Technology and Metrology (Astm Special Technical Pub No. 990)	Dinesh C. Gupta (Ed.)	July 1989
Simulation and Experiment in Laser Metrology		August 1996
Simulation and Experiment in Laser Metrology: Proceedings of the International Symposium on Laser Applications in Precision Measurements Held in bala	Zoltan Fuzessy (Ed.), et al	November 1996
Solar Cells: Their Optics and Metrology	Mark Mikhailovich Koltun	August 1990
Speckle Metrology	Rajpal S. Sirohi (Ed.)	
Speckle metrology		
Speckle Photography for Fluid Mechanics Measurements (Experimental Fluid Mechanics)	N. A. Fomin	September 1998
Statistical Metrology 2000 4th International Workshop	IEEE Staff (Ed.)	
Statistical Metrology, 1998 3rd Workshop	IEEE	July 1998
Strain and Stress Analysis by Holographic and Speckle Interferometry	V. P. Shchepinov (Ed.), et al	May 1996
The Coinage & Metrology of the Sultans of Delhi	H. Nelson Wright	June 1971
The Japanese Market for Metrology and Tooling Equipment		
The Metric System: And Its Corresponding Suffixes in Metrology: Mlg, M2, M3 for Everyday	John Serghi, Beatrice Hamor	June 1998
The Metrology of the Roman Silver Coinage	David Richard Walker	
The Nanopositioning Book. Moving and Measuring to Better than a Nanometre (Ultra Precision Technology)	Thomas R. Hicks, Paul Atherton	
The Origins of Metrology	Daniel M. McDonald	June 1992
The Physics of Moire Metrology	Oded Kafri, Ilana Glatt	
The World of Measurements: Masterpieces, Mysteries and Muddles of Metrology	H. Arthur. Klein	December 1974
Theoretical Metrology	T. Kemeny (Ed.), K. Havrilla (Ed.)	June 1987
Three-dimensional and unconventional imaging for industrial inspection and metrology : 23-25 October 1995, Philadelphia, Pennsylvania		
Three-Dimensional Imaging and Laser-Based Systems for Metrology and Inspection II: 20-21 November, 1996, Boston, Massachusetts		
Three-Dimensional Imaging and Laser-Based Systems for Metrology and Inspection III: 14-15 October, 1997, Pittsburgh, Pennsylvania		
Three-Dimensional Imaging, Optical Metrology, and Inspection IV: 2-3 November, 1998, Boston, Massachusetts (Proceedings of Spie--The International so	Kevin G. Harding (Ed.), et al	December 1998
Three-Dimensional Imaging, Optical Metrology, and Inspection V: Proceedings of Spie 19-20 September 1999 Boston, Massachusetts	Kevin G. Harding (Ed.)	December 1999
Tools of Metrology	Editors Quality Magazine	June 1984
Trends in Optical Fibre Metrology and Standards (NATO Asi Series. Series E, Applied Sciences, Vol 285)	Oliverio D. D. Soares (Ed.)	May 1995

Troisiáeme Symposium sur les âetalons de frâequence et la mâetrologie : 12-15 octobre 1981, Aussois, France : colloque international du C.N.R.S. = Third Symposium on Frequency Standards and Metrology		
Uncertainty of Measurements: Physical and Chemical Metrology: Impact & Analysis	S. K. Kimothi	June 2001
Uniform Laws and Regulations in the Areas of Legal Metrology and Engine Fuel Quality: As Adopted by the 84th National Conference on Weights and Measures, 1999	Thomas Coleman (Ed.), Terry L. Grimes (Ed.)	
Ursi Register of National Standards Laboratories for Electromagnetic Metrology	A.E. Bailey (Ed.)	January 1990
Vibration Control in Microelectronics, Optics, and Metrology: 4-6 November 1991 San Jose, California (Spie Proceedings, Vol 1619)	Colin G. Gordon (Ed.)	October 1992
Vibration Control in Optics and Metrology (Proceedings of Spie--The International Society for Optical Engineering, Vol 732)	L. R. Baker (Ed.)	July 1987
Vocabulary of legal metrology: fundamental terms		

Quadro E.2: pesquisa por publicações no site www.bn.com

NOME	AUTOR	EDITORA	MÊS/ANO
1998 3rd International Workshop on Statistical Metrology	IEEE, Electron Devices Society Staf	Institute of Electrical & Electronics	June 1998
1999 Ncsl Workshop and Symposium Proceedings: Metrology - at the Threshold of the Century Are We Ready?	National Conference Standards Laboratories Staf (Ed.)	National Conference of Standards Laboratories	July 1999
Accurate Visual Metrology from Single and Multiple Uncalibrated Images	Antonio Criminisi	Springer-Verlag New York, Incorporated	September 2001
Advanced Mathematical and Computational Tools in Metrology IV	P. Ciarlini (Ed.), F. Pavese (Ed.), A. B. Forbes (Ed.)	World Scientific Publishing Company, Incorporated	February 2000
Advanced Mathematical and Computational Tools in Metrology V	P. Ciarlini (Ed.), D. Richter (Ed.),E. Filipe (Ed.)	World Scientific Publishing Company, Incorporated	January 2001
Advanced Mathematical Tools in Metrology III	World Scientific Publishing Company Incorporated (Ed.)	World Scientific Publishing Company	September 1997
Advanced Process Module Equipment Control and Metrology	Cecil J. Davis, I. P. Herman, T. R. Turner	S P I E-International Society for Optical Engineering	February 1992
Advances in Optical Fabrication and Metrology Including Large Optics	J. B. Arnold (Ed.), R. E. Parks (Ed.)	S P I E-International Society for Optical Engineering	January 1989
Advancing Metrology for Electrotechnology to Support the U.S. Economy	Joanne Surette (Ed.)	DIANE Publishing Company	April 1999
Ancient Metrology	Donald L. Lenzen	Lenze, Donald L.	November 1989
Amplitude and Intensity Spatial Interferometry	Jim B. Breckinridge (Ed.)	S P I E-International Society for Optical Engineering	July 1990
Applied Radionuclide Metrology: Proceedings of the International Committee for Radionuclide Metrology Seminar, Geel, Belgium, 16-17 May 1983	G. C. Mann (Ed.), J. G. Taylor (Ed.), W. B. Mann (Ed.)	Elsevier Science	March 1984
Archaeological Metrology	Lester A. Ross	Canadian Government Pub Centre	December 1983
Art of Measurement: Metrology in Fundamental and Applied Physics	Bernhard J. Kramer (Ed.)	Wiley, John & Sons, Incorporated	January 1988
Basic Metrology for ISO 9000 Registration	G. M. de Silva	Butterworth-Heinemann	December 2001
Bcr Programme on Applied Metrology and Chemical Analysis Projects and Results, Vol. 148	UNIPUB (Ed.)	Bernan Associates	January 1992
Calibration Control Systems for the Biomedical and Pharmaceutical Industry: Rp-6	National Conference of Standards Laboratories in Healthcare Metrology Committe	National Conference of Standards Laboratories	May 1999

Characterization and Metrology for ULSI Technology: 1998 International Conference	David G. Seiler (Ed.), R. McDonald (Ed.), A. C. Diebold (Ed.),E. J. Walters (Ed.),T. J. Shaffner (Ed.),W. M. Bullis (Ed.)	American Institute of Physics	April 1999
Characterization and Metrology for ULSI Technology: 2000 International Conference with Cdrom	David G. Seiler, Et Al, A. C. Diebold	American Institute of Physics	February 2001
Christopher Columbus, Cosmographer: A History of Metrology, Geodesy, Geography, and Exploration from Antiquity to the Columbian Era	Fred F. Kravath	Landmark Enterprises	April 1988
Coherent Optical Metrology	Richard Kowarschik, Theo Tschudi, Lingli Wang	Wiley, John & Sons, Incorporated	May 2001
Comparative History of Metrology	H. J. Griffin (Ed.)	Continuum International Publishing Group Incorporated	January 1983
Computer Systems in Metrology: Recommended Practice Rp-13	National Conference of Standards Laboratories, Utilities Committee	National Conference of Standards Laboratories	February 1996
Critical Issues in Scanning Electron Microscope Metrology	Michael T. Postek	DIANE Publishing Company	December 1994
Digital Speckle Pattern Interferometry & Related Techniques	P. K. Rastogi (Ed.)	Wiley, John & Sons, Incorporated	December 2000
Dimensional Metrology and Geometric Conformance	Society Of Manufacturing Engineers (Ed.)	Society of Manufacturing Engineers	January 1988
Eeel Technical Accomplishments, 1998: Advancing Metrology for Electrotechnology to Support the U. S. Economy	JoAnne M. Surette, Geoffrey Wheeler (Photographer)	DIANE Publishing Company	September 1999
Electromagnetic Metrology: Proceedings of International Symposium on Electromagnetic Metrology, ISEM '89, August 19-22, 1989, Beijing, China	Chinese Society For Measurement Staff (Ed.)	Elsevier Science	January 1989
Engineering Metrology	D. M. Anthony	Butterworth-Heinemann	January 1986
Establishment and Operation of an Electrical Utility Metrology Laboratory: Rp-10	Utilities Committee Staff	National Conference of Standards Laboratories	August 1991
Fiber Optic Metrology and Standards, Vol. 150	Oliverio D. D. Soares	S P I E-International Society for Optical Engineering	August 1991
Flat Panel Display Technology and Display Metrology	Tolis Voutsas (Ed.), E. F. Kelley (Ed.)	S P I E-International Society for Optical Engineering	April 2001
Flat Panel Display Technology and Display Metrology: 27-29 January 1999, San Jose, California, Vol. 363	Bruce Gnade (Ed.), Edward F. Kelley (Ed.)	S P I E-International Society for Optical Engineering	January 1999
Frequency Standards and Metrology	Attilio De Marchi (Ed.)	Springer-Verlag New York, Incorporated	May 1989
Frequency Standards and Metrology: Proceedings of the Fifth Symposium	World Scientific Publishing Company Incorporated (Ed.)	World Scientific Publishing Company, Incorporated	May 1996
Frequency Standards and Metrology: Proceedings of the Sixth Symposium	Patrick Gill (Ed.)	World Scientific Publishing Company	June 2002
Fundamentals of Dimensional Metrology	Roger H. Harlow, Richard Thompson	Delmar Thomson Learning	October 2001
Fundamentals of Dimensional Metrology	Busch and Wilkie Brothers Foundation Staf	Delmar Thomson Learning	May 1964
Fundamentals of Dimensional Metrology	Busch	Delmar Thomson Learning	May 1964
Fundamentals of Dimensional Metrology	Busch	Delmar Thomson Learning	December 1964
Fundamentals of Dimensional Metrology	Busch and Wilkie Brothers Foundation Staf	Delmar Thomson Learning	January 1989
Fundamentals of Dimensional Metrology	Busch and Wilkie Brothers Foundation Staf	Delmar Thomson Learning	March 1986
Fundamentals of Dimensional Metrology	Busch	Delmar Thomson Learning	June 1997
Fundamentals of Dimensional Metrology	Ted Busch, Roger Harow, Richard L.	International Thomson Publishing	September 1998

	Thompson, Richard Thompson		
Gravitational Measurements, Fundamental Metrology and Constants	Venzo De Sabbata (Ed.), V. N. Melinkov (Ed.)	Kluwer Academic Publishers	June 1988
Handbook of Critical Dimension Metrology and Process Control	K. M. Monahan, Society of Photo-Optical Instrumentation Engineers Staff (Ed.)	S P I E-International Society for Optical Engineering	December 1994
Handbook of Industrial Metrology		Prentice Hall	January 1967
Handbook of Silicon Semiconductor Metrology	Alain C. Diebold (Ed.)	Marcel Dekker	January 2001
Handbook of Surface Metrology	David J. Whitehouse, D. J. Whitehouse (Ed.)	Iop Pub	January 1994
Holographic and Speckle Interferometry	Robert Jones, Catherine M. Wykes	Cambridge University Press	March 1989
Holographic and Speckle Interferometry	Robert Jones, Catherine M. Wykes	Cambridge University Press	March 1983
Holographic and Speckle Interferometry: A Discussion of the Theory, Practice, and Application of the Techniques	Robert Jones, Jones Wykes, Jones/Wykes	Cambridge University Press	January 1989
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